

Title (en)
MICROFABRICATED TEMPLATE FOR MULTIPLE CHARGED PARTICLE BEAM CALIBRATIONS AND SHIELDED CHARGED PARTICLE BEAM LITHOGRAPHY

Title (de)
MIKROTECHNOLOGISCH HERGESTELLTE BLENDE FÜR DIE AUSRICHTUNG VON TEILCHENSTRAHLENQUELLEN SOWIE FÜR DIE UNTERDRÜCKUNG DER SUBSTRATAUFLADUNG IN DER TEILCHENSTRAHLLITHOGRAPHIE

Title (fr)
MODELE MICROFABRIQUE POUR CALIBRATIONS DE FAISCEAUX A MULTIPLES PARTICULES CHARGEES ET LITOGRAPHIE DE FAISCEAUX A PARTICULES CHARGEES PROTEGEES

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Application
EP 00929001 A 20000503

Priority
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• US 30450599 A 19990503

Abstract (en)
[origin: WO0067291A2] A method, an associated structure, and an apparatus for multiple charged particle beam calibration and shielded charged particle lithography. A template defining an array of membranes is positioned above a target (e.g., a semiconductor wafer of the electron beams). Each membrane defines a through slot (opening) and a set of registration marks which are located with respect to registration marks of the other membranes. Patterns are written onto the target by scanning each electron beam through its associated through slot. Intra- and inter-charged particle beam calibrations for each charged particle beam are carried out using its associated set of registration marks. The template also suppresses undesirable electrical charging of any resist present on the target during the exposure process.

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